

Title (en)

Pump and method of manufacturing same

Title (de)

Pumpe und ihr Herstellungsverfahren

Title (fr)

Pompe et sa méthode de fabrication

Publication

EP 1253320 A3 20040204 (EN)

Application

EP 02008979 A 20020423

Priority

JP 2001125904 A 20010424

Abstract (en)

[origin: EP1253320A2] A compact pump has a pump chamber, inlet and outlet channels communicating with the pump chamber, and a pair of check valve units between the pump chamber and the inlet and outlet channels. Each check valve unit has a thin film check valve membrane, and a check valve body with a channel opened and closed by the check valve membrane due to a pressure difference. <IMAGE>

IPC 1-7

F04B 43/04; F04B 53/10

IPC 8 full level

F04B 43/00 (2006.01); **F04B 43/04** (2006.01); **F04B 53/10** (2006.01)

CPC (source: EP KR US)

F04B 43/00 (2013.01 - KR); **F04B 43/04** (2013.01 - EP US); **F04B 53/1062** (2013.01 - EP US)

Citation (search report)

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- [XA] EP 0789146 A1 19970813 - SEIKO EPSON CORP [JP]
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Designated contracting state (EPC)

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DOCDB simple family (publication)

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DOCDB simple family (application)

EP 02008979 A 20020423; CN 02118459 A 20020424; DE 60209054 T 20020423; HK 03101906 A 20030314; KR 20020022511 A 20020424; TW 91107782 A 20020416; US 12753502 A 20020423